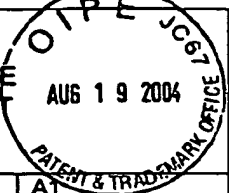
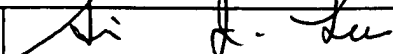


Substitute form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number		10/800,195	
		Filing Date		03/12/04	
		First Named Inventor		Dai	
		Group Art Unit		1752	
		Examiner Name		Unknown	
Sheet	A1	of	A1	Attorney Docket Number	5347-218

U.S. PATENTS AND PATENT PUBLICATIONS					
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
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Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T	
		Office	Number	Kind Code (if known)				

OTHER NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published			T
SJL	3.	Dai et al. "Organoelement resists for EUV lithography," <u>SPIE The International Society for Optical Engineering</u> 4690:1193-1202 (2002)			

Examiner Signature		Date Considered	4-3-05
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.